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Atomic Processes in Plasmas: APiP-2019

Guest Editors:

Dr. Yuri Ralchenko

Atomic Spectroscopy Group, Quantum Measurement Laboratory, National Institute of Standards and Technology, Gaithersburg, MD, USA

Dr. Alexander Kramida

Atomic Spectroscopy Group, Physical Measurement Laboratory, Quantum Measurement Division, National Institute of Standards and Technology, Gaithersburg, MD, 20899-8422. USA

Deadline for manuscript submissions: **closed (23 June 2019)**

Message from the Guest Editors

Dear Colleagues,

This Special Issue will contain the invited and some contributed talks from the 20th International Conference on Atomic Processes in Plasmas that will be held at NIST, Gaithersburg MD from 9 to 12 April 2019.

Dr. Yuri Ralchenko Dr. Alexander Kramida *Guest Editors*











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Editor-in-Chief

Dr. James F. Babb

Institute for Theoretical Atomic and Molecular Physics, Center for Astrophysics | Harvard & Smithsonian, Cambridge, MA 02138, USA

Message from the Editor-in-Chief

The scope of *Atoms* is deliberately wide and encompasses a large part of theoretical and experimental atomic, molecular, nuclear, and chemical physics in order to encourage cross-disciplinary connections, while supporting the more traditional idea of individual subfields. The journal is also interested in papers concerning

the computation and compilation of data related to applications in the above areas. Details of experimental methods and codes are welcome. Your research is taken seriously and peer-reviewed with care. I encourage you to contact me or any of the Editorial Board Members for further information.

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